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APPLICATION THAT MET THE REQUIREMENTS TO BE GRANTED A
FILING DATE.

APPLICATION NUMBER: 60/363,139

FILING DATE: March 08, 2002

RELATED PCT APPLICATION NUMBER: PCT/US03/07123

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U.S. Patent and Trademark Office, U.S. DEPARTMENT OF COMMERCE**PROVISIONAL APPLICATION FOR PATENT COVER SHEET**

This is a request for filing a PROVISIONAL APPLICATION FOR PATENT under 37 CFR 1.53(c).

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INVENTOR(S)		
Given Name (first and middle [if any]) Mark N.	Family Name or Surname Horenstein	Residence (City and either State or Foreign Country) West Roxbury, MA 02132

 Additional inventors are being named on the _____ separately numbered sheets attached hereto**TITLE OF THE INVENTION (500 characters max)****METHOD FOR LINEARIZING DEFLECTION OF A MEMS DEVICE USING BINARY ELECTRODES AND VOLTAGE MODULATION**

Direct a. correspondence to:

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ENCLOSED APPLICATION PARTS (check all that apply) Specification Number of Pages

6

 CD(s), Number

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 Other (specify)

 Application Data Sheet. See 37 CFR 1.76**METHOD OF PAYMENT OF FILING FEES FOR THIS PROVISIONAL APPLICATION FOR PATENT** Applicant claims small entity status. See 37 CFR 1.27.FILING FEE
AMOUNT (\$)

A check or money order is enclosed to cover the filing fees

 The Commissioner is hereby authorized to charge filing
fees or credit any overpayment to Deposit Account Number:

023255

\$80.00

 Payment by credit card. Form PTO-2038 is attached.The invention was made by an agency of the United States Government or under a contract with an agency of the
United States Government. No. Yes, the name of the U.S. Government agency and the Government contract number are: _____

Respectfully submitted,

SIGNATURE Mark N. Horenstein

Date 03/08/2002

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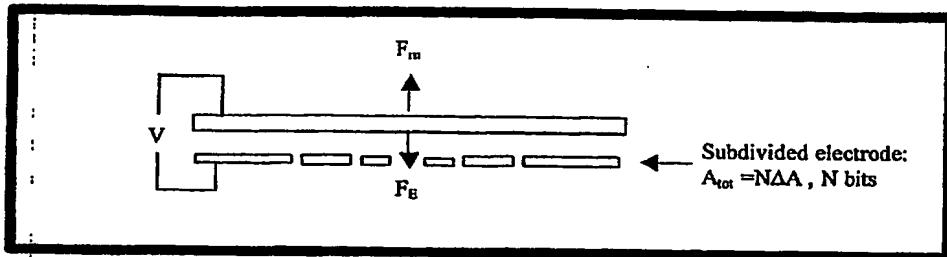
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USE ONLY FOR FILING A PROVISIONAL APPLICATION FOR PATENT

This collection of information is required by 37 CFR 1.51. The information is used by the public to file (and by the PTO to process) a provisional application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 8 hours to complete, including gathering, preparing, and submitting the complete provisional application to the PTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, Washington, D.C. 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Box Provisional Application, Assistant Commissioner for Patents, Washington, D.C. 20231.

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Notes on Multi-Electrode System
28 November 2001



Governing Equations

$$F_m = \frac{192EIx}{L^3}$$

Mechanical restoring force for a given displacement, x

$$F_E = \frac{\epsilon AV^2}{2(g-x)^2}$$

Electrostatic Force

Equilibrium occurs when $F_m = F_E$:

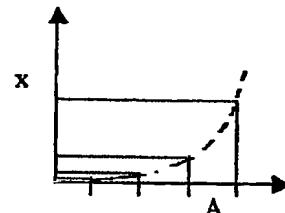
$$A = \frac{C}{V^2}x(g-x)^2 = \frac{C}{V^2}[x^3 - 2gx^2 + g^2x]$$

where,

$$C = \frac{384EI}{L^3\epsilon}$$

Problem:

Deflection, "x", is a strongly non-linear function of area, "A". Therefore, actuation approach based on fixed voltage and uniform increments in A will not lead to uniform increments in phase.



Mathematically:

$$A = \frac{C}{V^2} x(g-x)^2 = \frac{C}{V^2} [x^3 - 2gx^2 + g^2x]$$

$$\frac{dA}{dx} = \frac{C}{V^2} [3x^2 - 4gx + g^2]$$

so: $\frac{dx}{dA} = \frac{V^2}{C[3x^2 - 4gx + g^2]}$

An estimate of the largest step in "x" made by uniformly increasing "A" is:

$$\Delta x_m \doteq \frac{dx}{dA} \Big|_{x_m} \cdot \Delta A$$

where x_m in the maximum required value of x; Δx_m in the maximum x step.

But: $\Delta A = \frac{A_{tot}}{2^n - 1}$ by design

And $A_{tot} = \frac{C}{V^2} x_m (g - x_m)^2$ by model

therefore

$$\Delta x_m = \frac{V^2 C x_m (g - x_m)^2}{C V^2 [2^n - 1] [3x_m^2 - 4gx_m + g^2]}$$

simplifying:

$$\frac{x_m}{\Delta x_m} = \frac{(2^n - 1)(g - 3x_m)}{(g - x_m)}$$

The resolution of the actuator can be defined as one part in M, where

$$M = \frac{x_m}{\Delta x_m}$$

$$\therefore M = \left(\frac{g - 3x_m}{g - x_m} \right) (2^n - 1)$$

Non-linearity is worst for $g = 3x_m$, and improves as g increases.

Example:

$$g = 3.1x_m$$

$$M = \left(\frac{0.1}{2.1} \right) (2^n - 1)$$

Factor of 20+ loss of resolution (e.g. 8 bit system provides ~3 bit resolution)

Resolution Reduction Factor, R is:

$$\frac{1}{R} = \left(\frac{g - 3x_m}{g - x_m} \right)$$

Improvement in resolution is possible, by increasing "g".

<u>g</u>	<u>R</u>	
$3.1x_m$	21	(~silicon single-gap structures)
$4x_m$	3	
$5x_m$	2	<i>if $g \geq 5x_m$, only 1 bit of resolution is lost</i>
$6.7x_m$	1.5	<i>silicon double-gap structures</i>

Price: Increase driving voltage

$$V^2 = \frac{C}{A} x (g - x)^2$$

therefore:

$$\left(\frac{V_2}{V_1} \right)^2 = \frac{C/A x_m (g_m - x_m)^2}{C/A x_m (g_m - x_m)^2}$$

and

$$\frac{V_2}{V_1} = \frac{g_2 - x_2}{g_1 - x_1}$$

is the ratio of maximum required voltages for two different gaps. C, A , and x_m unchanged.

If $g_2 = 5x_m$, and $g_1 = 3x_m$,

$$V_2 = 2V_1$$

Alternative solution: Linearize

$$AV^2 = Cx(g - x)^2$$

this could be linearized by imposing the constraint that:

$$V^2 \propto (g - x)^2 \text{ or } V = k(g - x)$$

then $A = \frac{C}{k^2} x$

find value of k:

$$A_{tot} = \frac{C}{k^2} x_m \quad k = \sqrt{\frac{Cx_m}{A_{tot}}}$$

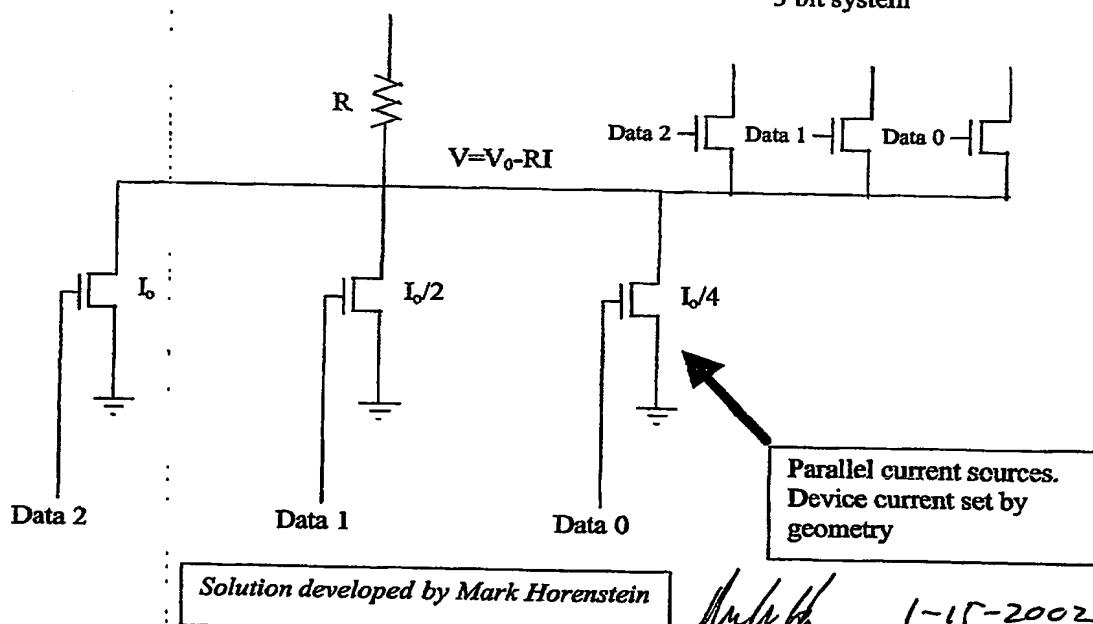
For the silicon structures with a 2.5 μm gap: $V_i \sim 70\text{V}$ and $V_f \sim 50\text{V}$

How to make $V = k(g - x)$?

Input to system (binary) is a linear representation of x. Use the data bus to modify voltage to each actuator:

$$V_0 = kg$$

3 bit system

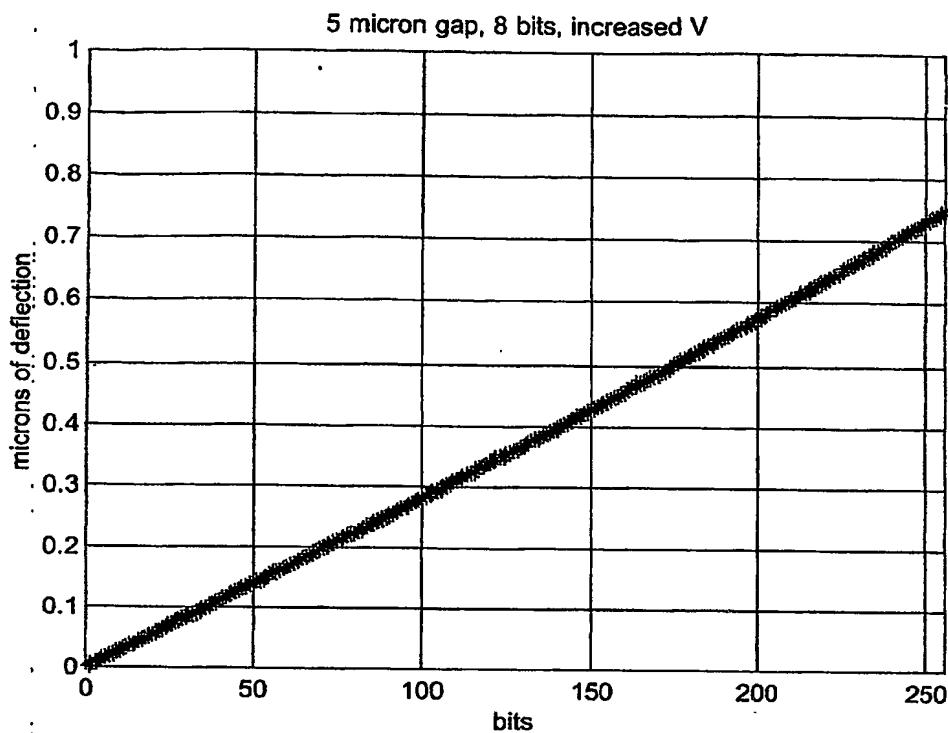


Solution developed by Mark Horenstein

Mark Horenstein 1-15-2002

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Model of an 8 bit system, with a $5 \mu\text{m}$ gap using the linearized voltage solution ($V_i = 130\text{V}$)



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%--MATLAB PROGRAM--
%Example of linearizing the deflection versus digital input curve.
%Requires that the voltage applied to the electrodes be reduced as
%the digital input n goes up from 0 to N (where N = 16, 128, 256, etc)
close; clear; %close any previous plots and reset
variables
N=256;
input 2^n where n=0...N (8 bits in this example)
k = 60; %Maximum value of digital
N/m (typical) %elastic restoring force in
eo = 8.85e-12; %electric permittivity of air
side = 250e-6; %dimension of each side of actuator
Area = side^2; %total area of actuator
Ao=Area/N; %smallest increment of area
(Area increment per digital bit)
gap = 5e-6; %spacing between actuator and
activation electrode %incremental deflection to be used
dy = gap/1000;
in iteration

for n=1:N;
n for n=1...N:
    V=40*(1-n/(8*N)); %V is a function of n. Equal to 40 V at start, decreases
    %in a straight line
function with n. I think we can do this
    %in a straightforward manner electronically in VLSI.

%----Iteration to solve for deflection y as a function of digital input n ----
y=0; %initial deflection to zero
Fm = k*y; %Compute magnitude of
mechanical force
Fe = eo*Ao*n*V^2/(2*(gap-y)^2); %Compute magnitude of electrostatic force
    %(Total area is n times Ao)
while Fm < Fe;
    y = y + dy; %Try a slightly larger
    %Recompute magnitude of
    %mechanical force
    Fe = eo*Ao*n*V^2/(gap-y)^2; %Recompute magnitude of electrostatic force
    %Get
    %out of loop when Fm = Fe.
end
Y(n)=y; %Save this value of y(n) for
later plotting %Iterate over all
end
values of n from 0...N
%Done with iteration
plot(Y*1e6) %Plot deflection in microns
versus n

%Suggestions: variations on the program:
%Set V to a fixed 40 V; this change will demonstrate non-linearity in area vs n
curve.
%Set V to 40*(n/N) and change Ao*n to Area; this change produces the usual nonlinear
%deflection versus voltage curve.

```